

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. SEPP14.001C1	APPLICATION NO. Unknown
	APPLICANT Janne Kesala	
	FILING DATE Herewith	GROUP Unknown

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
RRB	1	4,058,430	11/15/77	Suntola et al.			
RRB	2	4,389,973	06/1983	Suntola et al.			
RRB	3	5,855,680	01/05/99	Solninen et al.			

FOREIGN PATENT DOCUMENTS								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
RRB	4	WO 01/36702 A1	05/25/01	PCT				

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)							
RRB	5	M. Leskela et al., "Synthesis of oxide thin films and overlayers by atomic layer epitaxy for advanced applications," Materials Science & Engineering, Vol. B41 (1996), pages 23-29.						
RRB	6	Niinisto et al., "ALD precursor chemistry: evolution and future challenges," Journal de Physique IV. Vol. 9 (1999), pages Pr8-837-Pr8-852.						
RRB	7	Pierson, Handbook of Chemical Vapor Deposition, (1992), pp.87-88.						
RRB	8	Tuomo Suntola, "Atomic Layer Epitaxy," Thin Solid Films, Vol 216 (1992), pages 84-89.						

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EXAMINER <i>R Bure</i>	DATE CONSIDERED <i>3 - 2005</i>
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	